

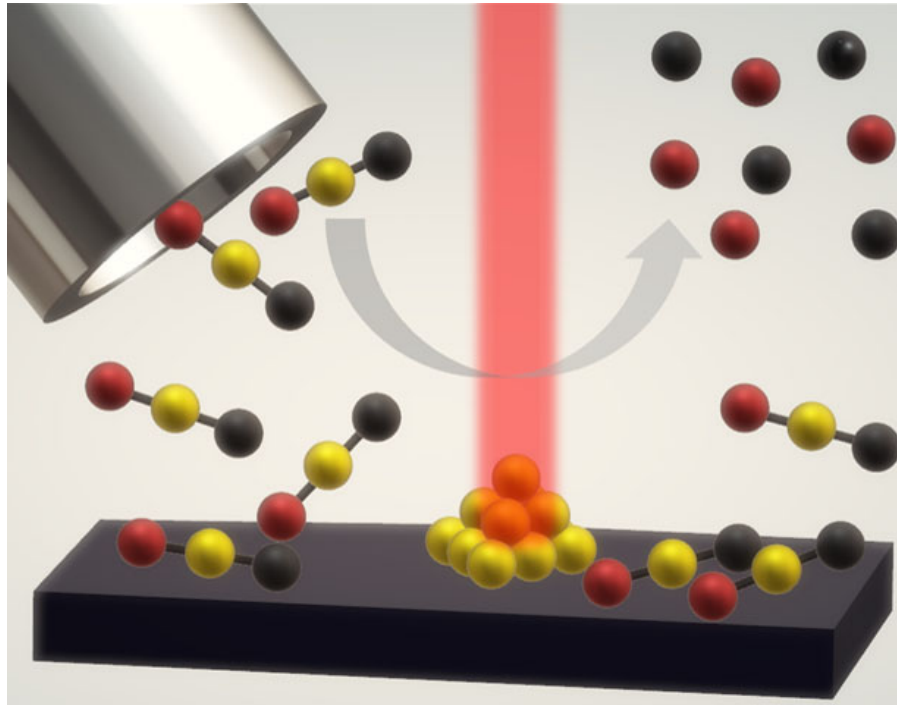
# Precursors for Focused Electron Beam Induced Deposition (FEBID) of Nanostructures

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Department of Chemistry  
University of Florida

# FEBID\* of Metal Nanostructures

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\*Focused Electron Beam Induced Deposition

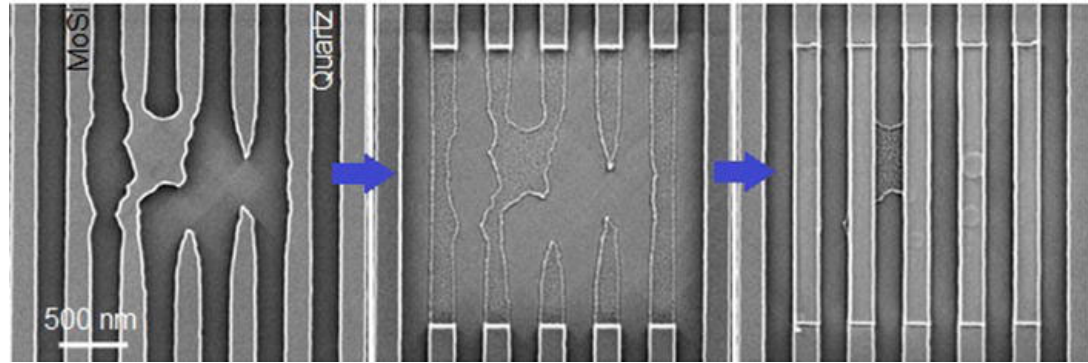


Precursor design for FEBID: Spencer, Rosenberg, Barclay, Wu, McElwee-White, Fairbrother, *Appl. Phys. A.*, **2014**, 117, 163  
Carden, Lu, Spencer, Fairbrother, McElwee-White, *MRS Commun.*, **2018**, 8, 343

# FEBID Applications

## Industrial Applications

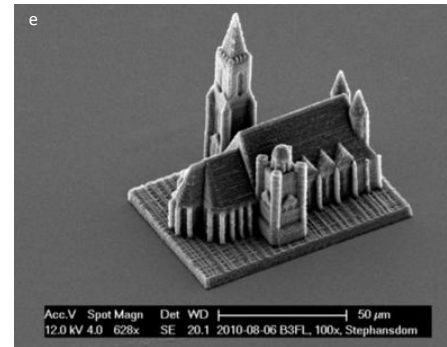
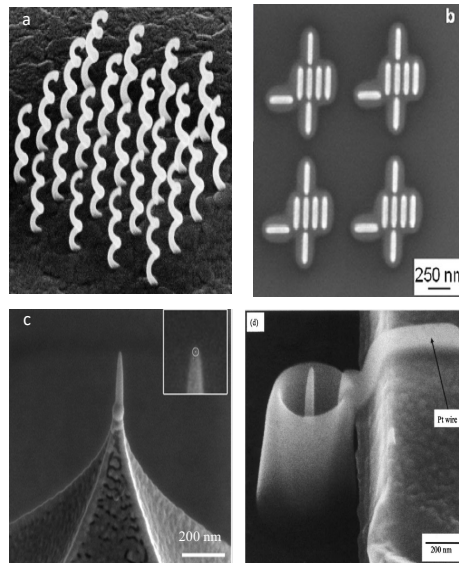
- Photomask repair
- Circuit edit



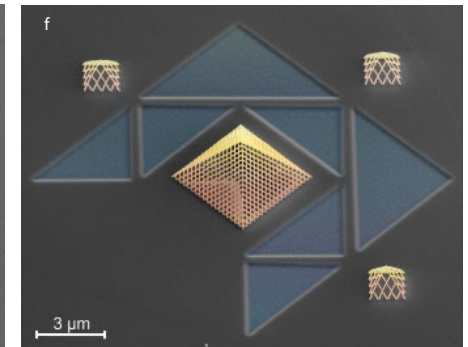
Bret, *Appl. Phys. A: Mater. Sci. Process.* **2014**, 117, 1607

## Academic Research

- Diodes
- Photonic crystals
- Probes
- Electron sources
- Conducting wires
- Seeds for nanotube growth
- Nanosoldering



- (a) Silica/Au nanoplasmonic array
- (b) Fe nanowires
- (c) Pt AFM tip
- (d) Pt source for I-V measurements
- (e) Stephansdom model
- (f) Louvre pyramid model



Images from the work of Acar, Wanzenboeck, Brown, Murakami, Plank, Winkler

# FEBID of Metal Nanostructures – What's Important

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Precursor decomposition:      electron bombardment  
   thermal (surface)

Important considerations:

1. Composition of deposited material
  - Clean ligand loss upon  $e^-$  attachment or surface binding
2. Precursor volatility
  - Required for gas phase delivery
3. Thermal stability
  - Precursor decomposition temperature must be high to avoid CVD

Precursor design for FEBID: Spencer, Rosenberg, Barclay, Wu, McElwee-White, Fairbrother, *Appl. Phys. A.*, **2014**, 117, 163  
Carden, Lu, Spencer, Fairbrother, McElwee-White, *MRS Commun.*, **2018**, 8, 343

# Why Use CVD Precursors for FEBID?

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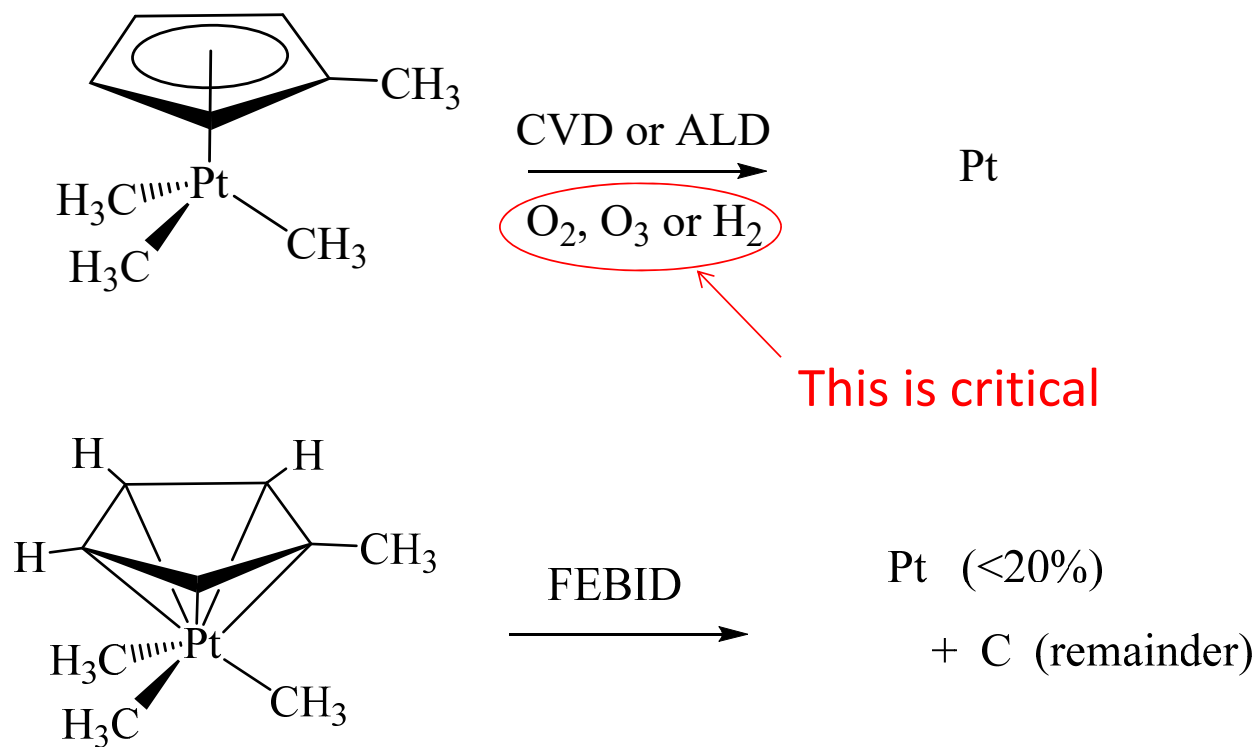
1. They are commercially available
2. They are volatile
3. They have been demonstrated to decompose to some desired material...

...under some set of deposition conditions

Precursor design for CVD: McElwee-White, *Dalton Trans.* **2006**, 5327  
McElwee-White, Koller, Kim, Anderson, *ECS Transactions*, **2009**, 25, 161

Precursor design for FEBID: Spencer, Rosenberg, Barclay, Wu, McElwee-White, Fairbrother, *Appl. Phys. A.*, **2014**, 117, 1631  
Carden, Lu, Spencer, Fairbrother, McElwee-White, *MRS Commun.*, **2018**, 8, 343

# Why Not Use CVD Precursors for FEBID?

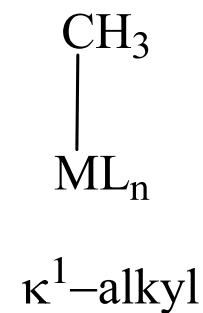
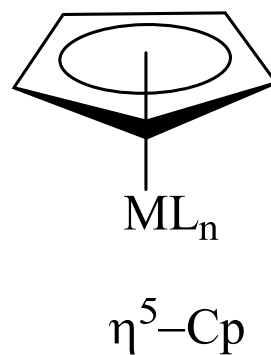
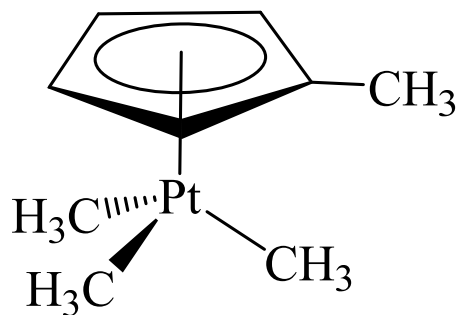


Xue, Strouse, Shuh, Knobler, Kaesz, Hicks, Williams, *J. Am. Chem. Soc.*, **1989**, *111*, 8779

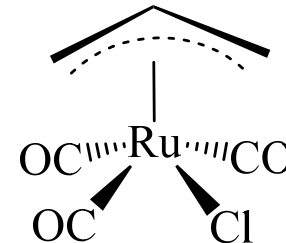
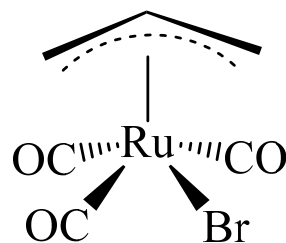
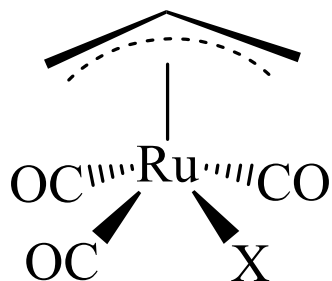
Botman, Hesselberth, Mulders, *Microelectron. Eng.* **2008**, *85*, 1139

# Thinking About Ligands

Design: What do we learn from  $\text{Cp}'\text{PtMe}_3$  ?

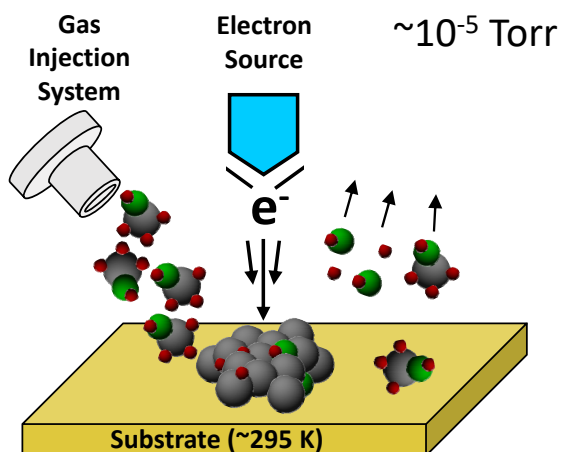


Test Precursors:



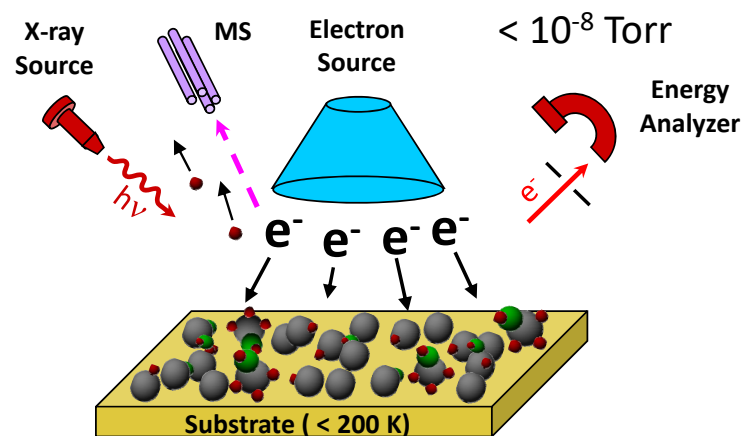
# Applying a UHV Surface Science Approach

## Typical FEBID Experiment



- Constant partial pressure of precursor
- Substrate at room temperature
- Focused electron beam (20 – 200 KeV)
- Size scale:  $\sim \text{nm}^3$
- Analytical techniques: SEM, EDX
- Information obtained: composition and dimensions of deposited structure

## UHV Surface Science Approach

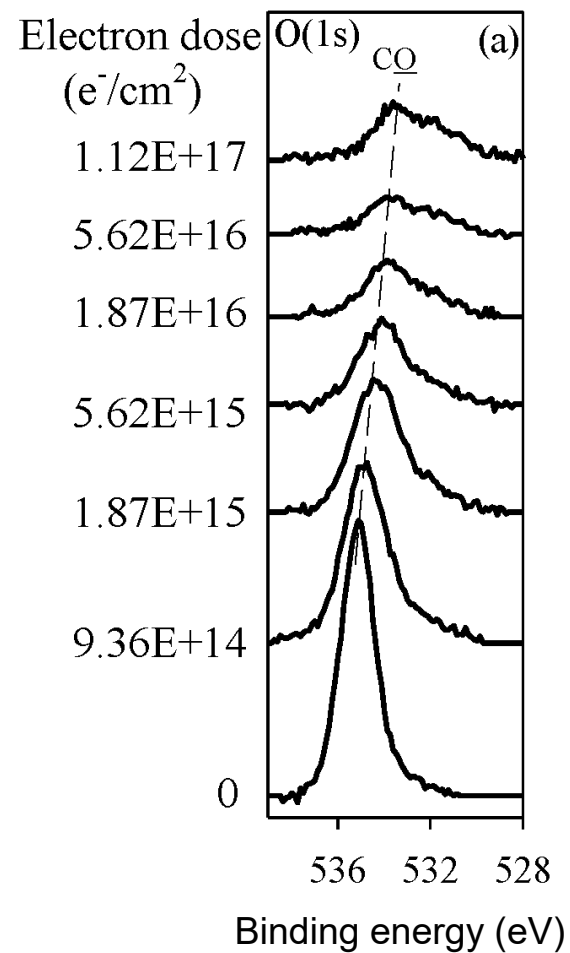
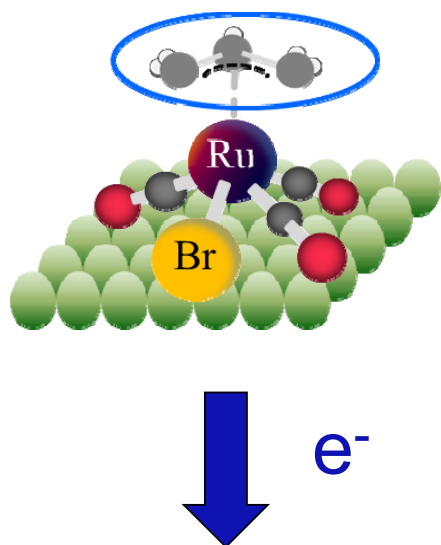


Graphic (and Experiments): Howard Fairbrother

- Fixed initial coverage of precursor molecules
- Substrate cooled to  $< 200\text{K}$
- Defocused low energy electron beam (0.5 KeV)
- Size scale:  $\sim \text{cm}^2$
- Analytical techniques: XPS, MS
- Information obtained: kinetic and mechanistic details of precursor decomposition

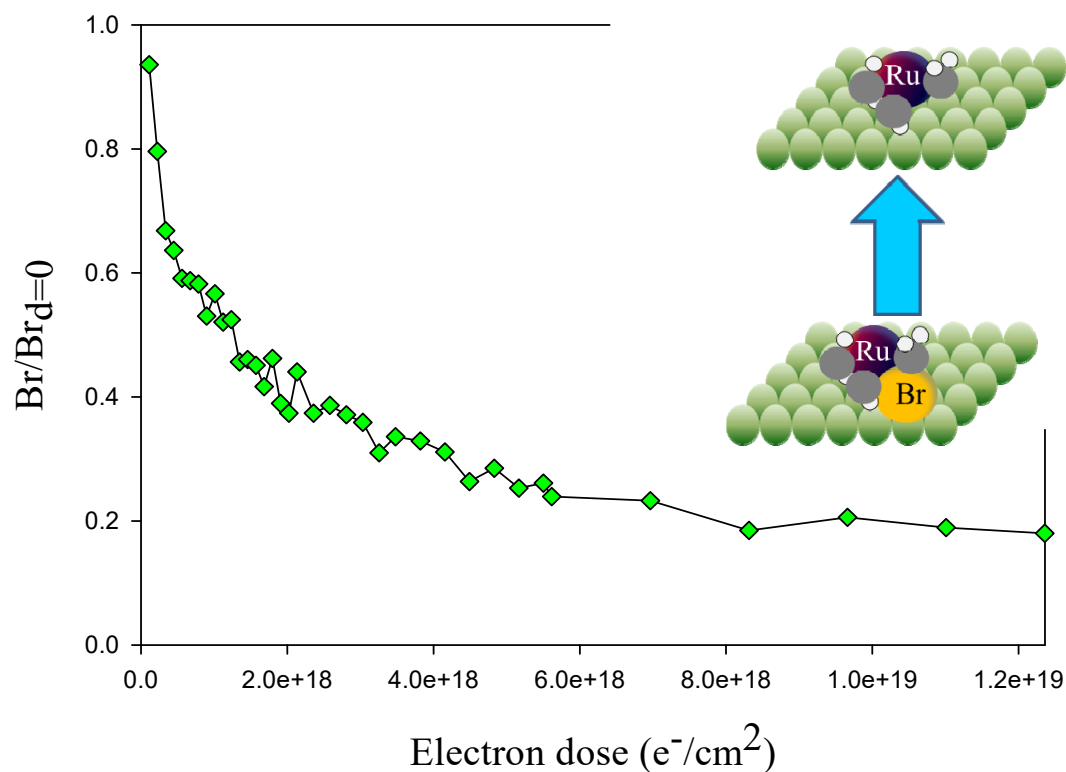
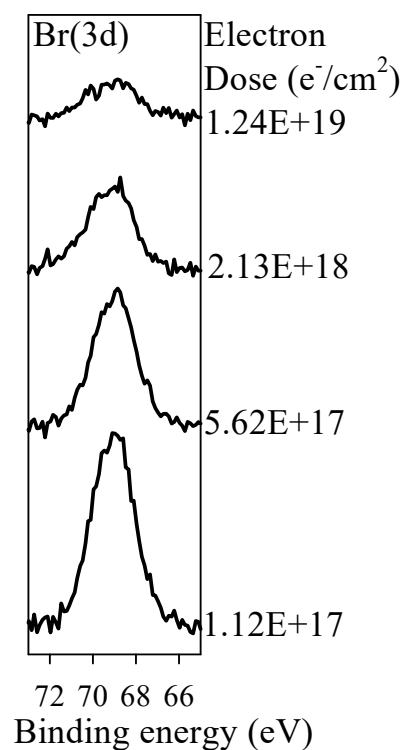


# Experiment: Fate of CO



# But...

...halogens can be removed by post-deposition processing

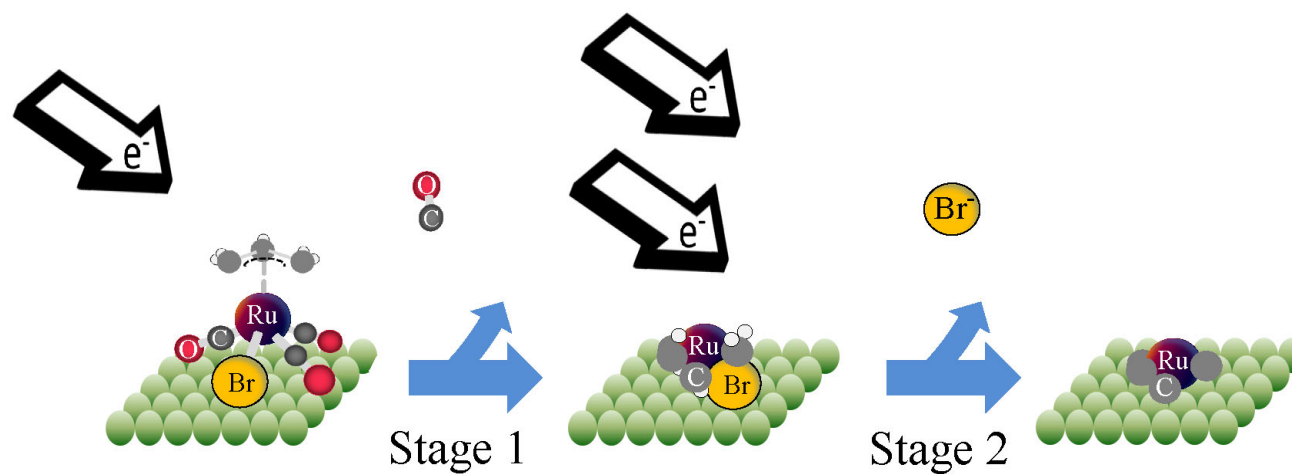


# And the carbon?

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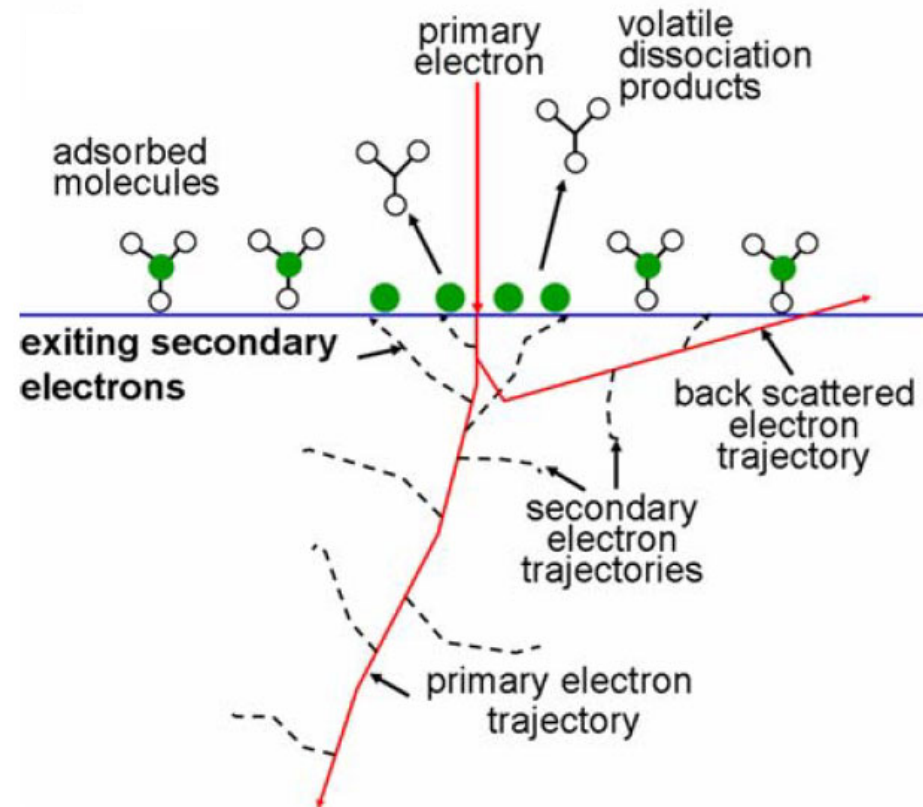
Well, it's still there...

...but we learned something.



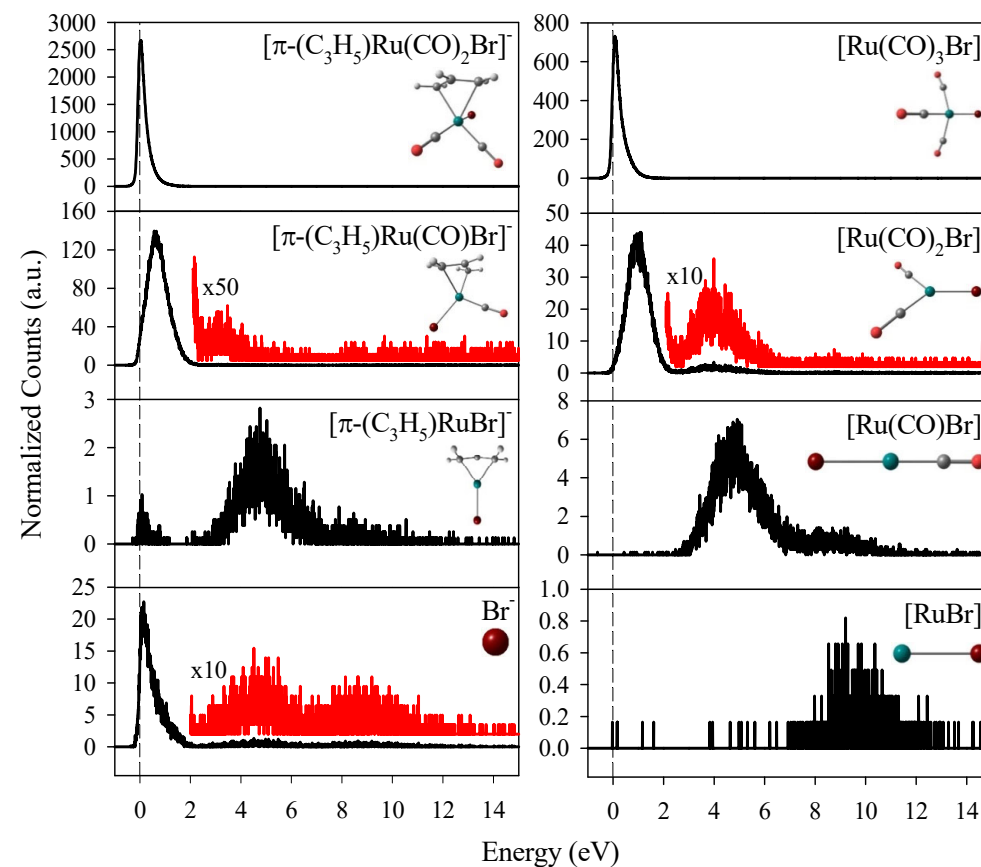
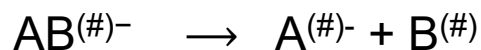
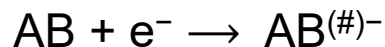
# Secondary Electrons

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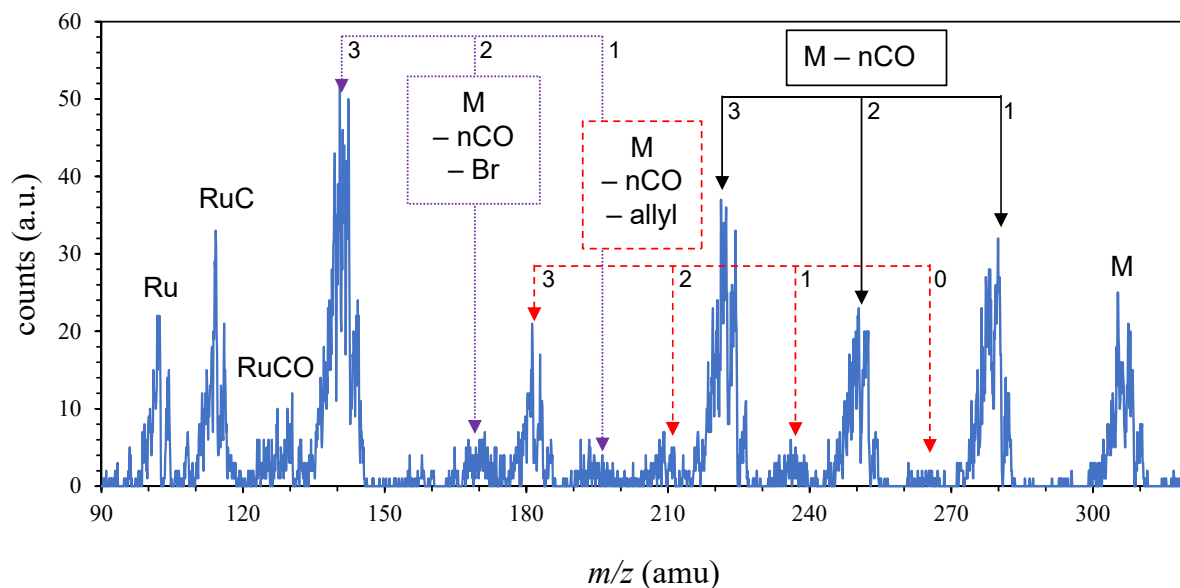
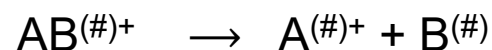
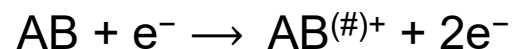
# Gas Phase Electron-Molecule Interactions

Low energy electrons  
→ dissociative electron  
attachment (DEA)

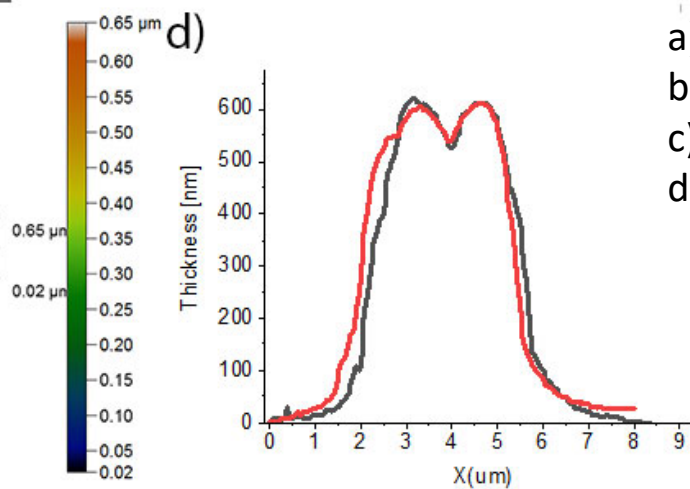
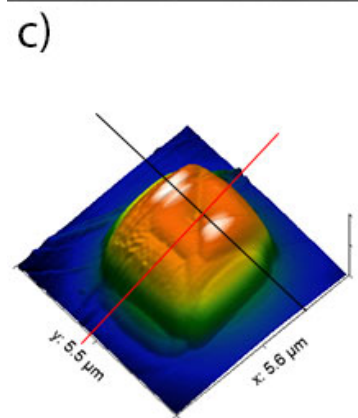
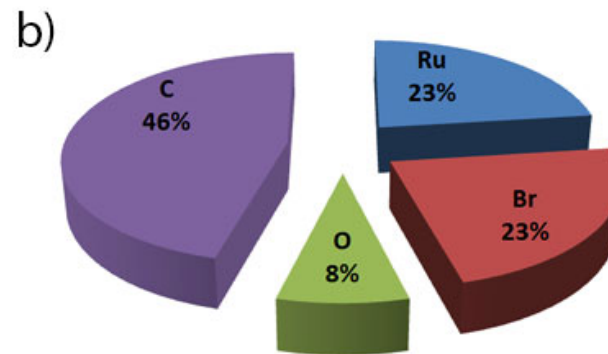
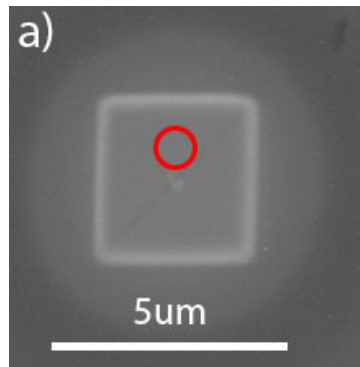


# Gas Phase Electron-Molecule Interactions

High energy electrons (75 eV)  
→ dissociative ionization (DI)

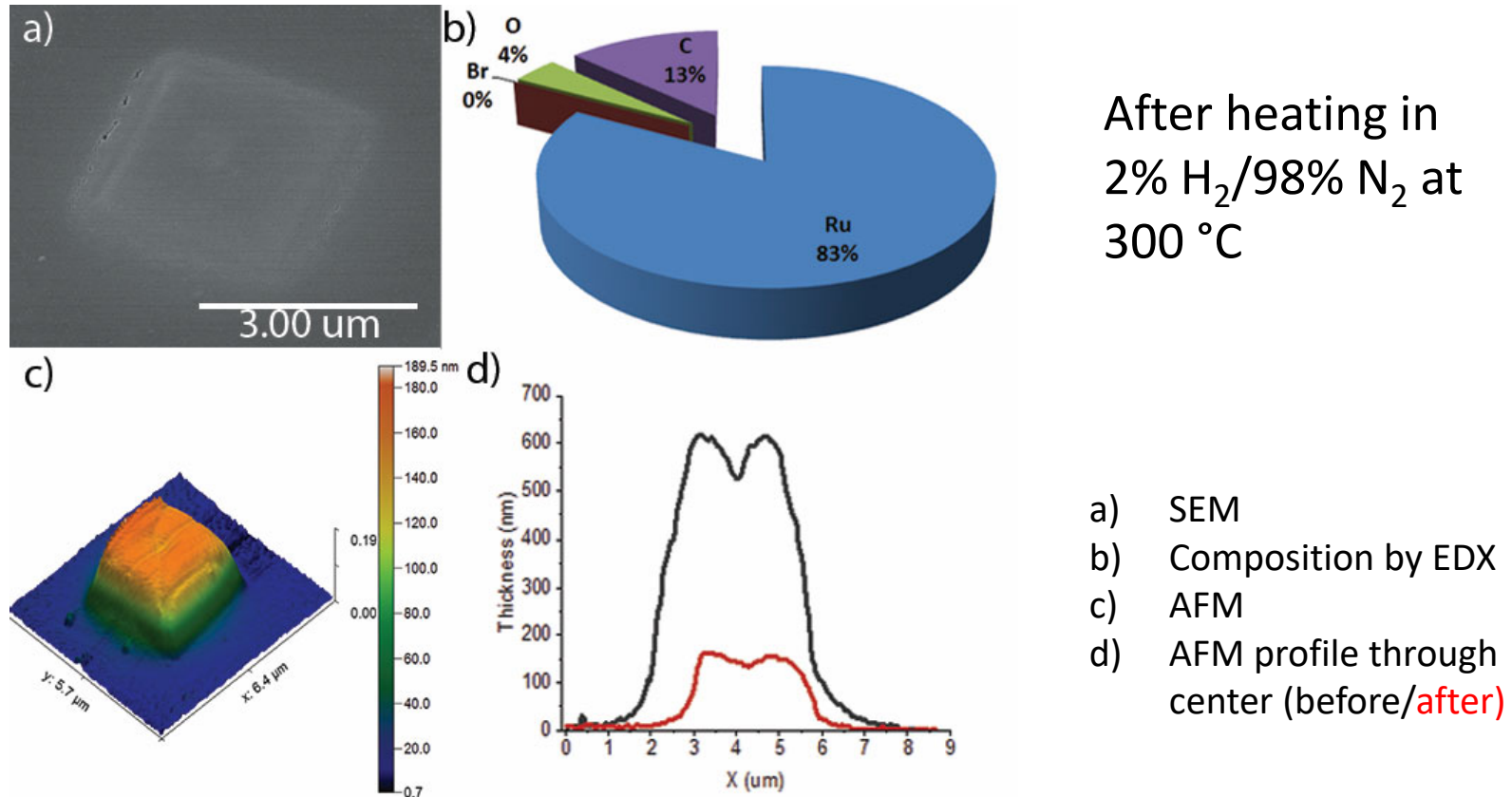


# FEBID of Ru



- a) SEM
- b) Composition by EDX
- c) AFM
- d) AFM profiles through center

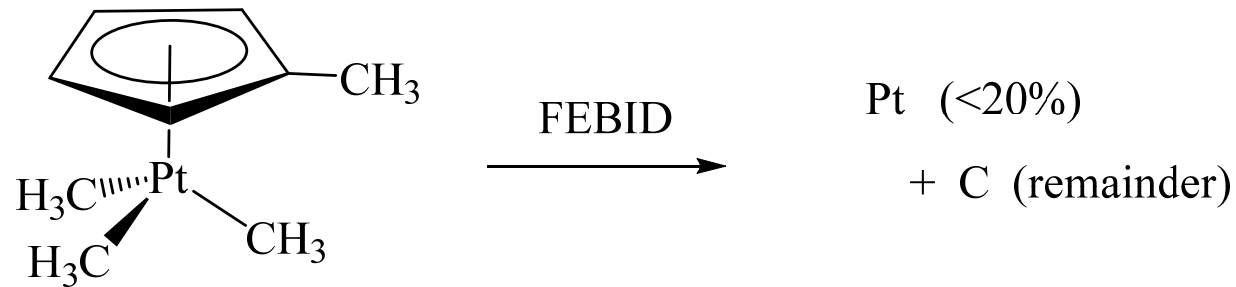
# FEBID of Ru – With Purification





# Revisiting the Pt problem...

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Botman, Hesselberth, Mulders, *Microelectron. Eng.* **2008**, 85, 1139

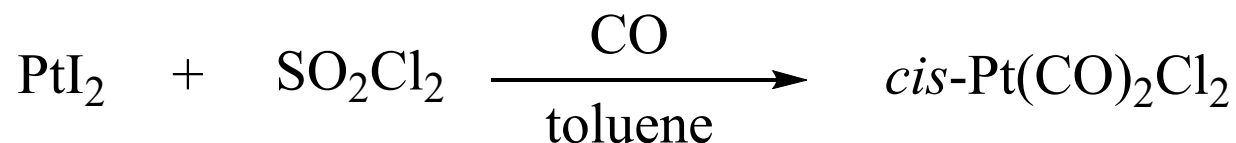
...with what we learned about design rules

- $\pi$ -Facial carbon ligands don't dissociate well on the surface
- CO can dissociate readily in early stage  $e^-$  flux
- Halide ligands can be removed by continued  $e^-$  flux

# *cis*-Pt(CO)<sub>2</sub>Cl<sub>2</sub>

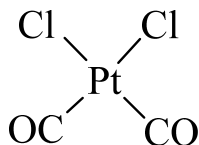
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## Synthesis



Bagnoli *et al*, *J. Chem. Soc., Dalton Trans.*, **1996**, 4317

## Characterization



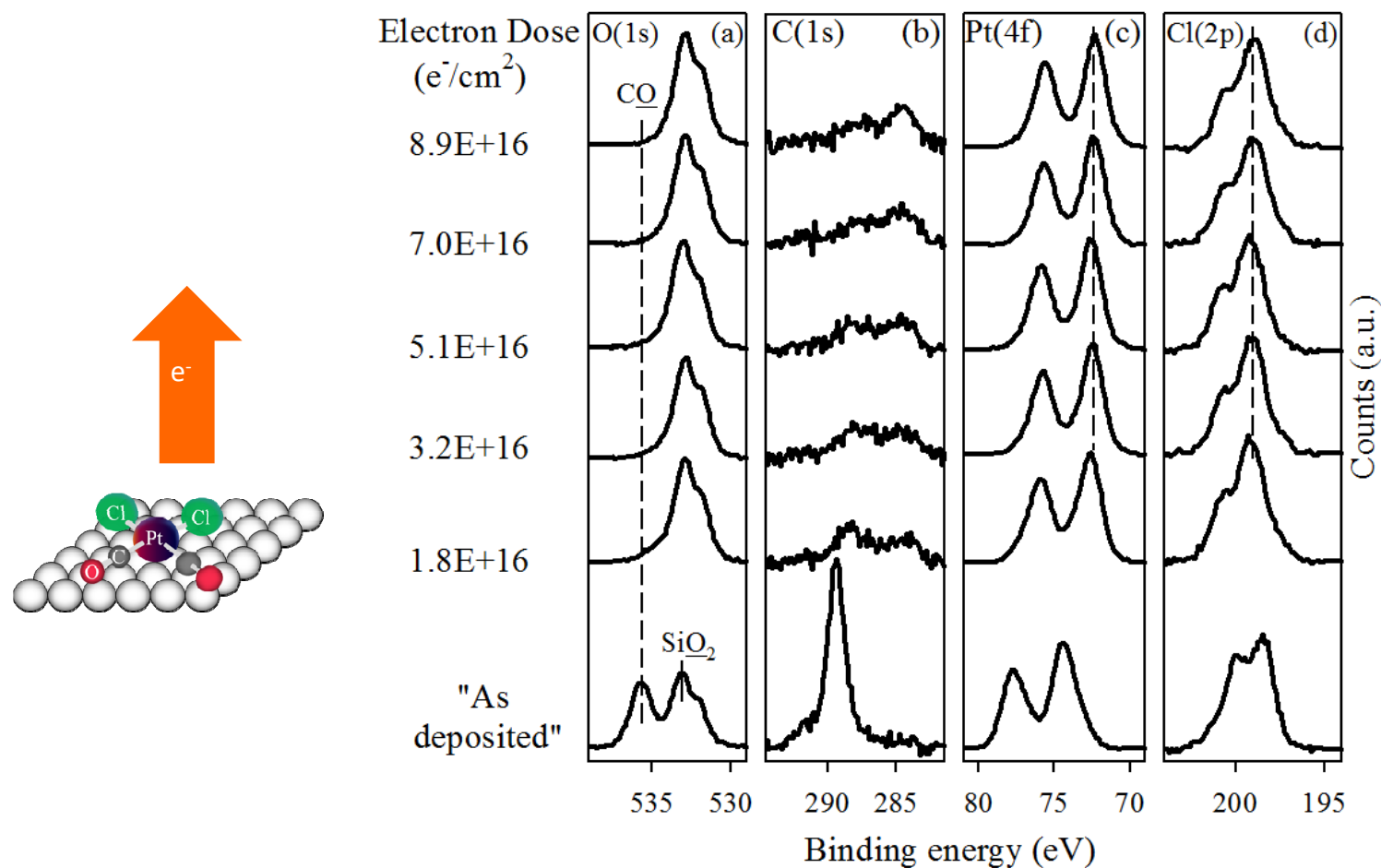
IR:  $\nu_{\text{CO}}$  2127, 2171  $\text{cm}^{-1}$

$^{13}\text{C}$  NMR:  $\delta$  151.84

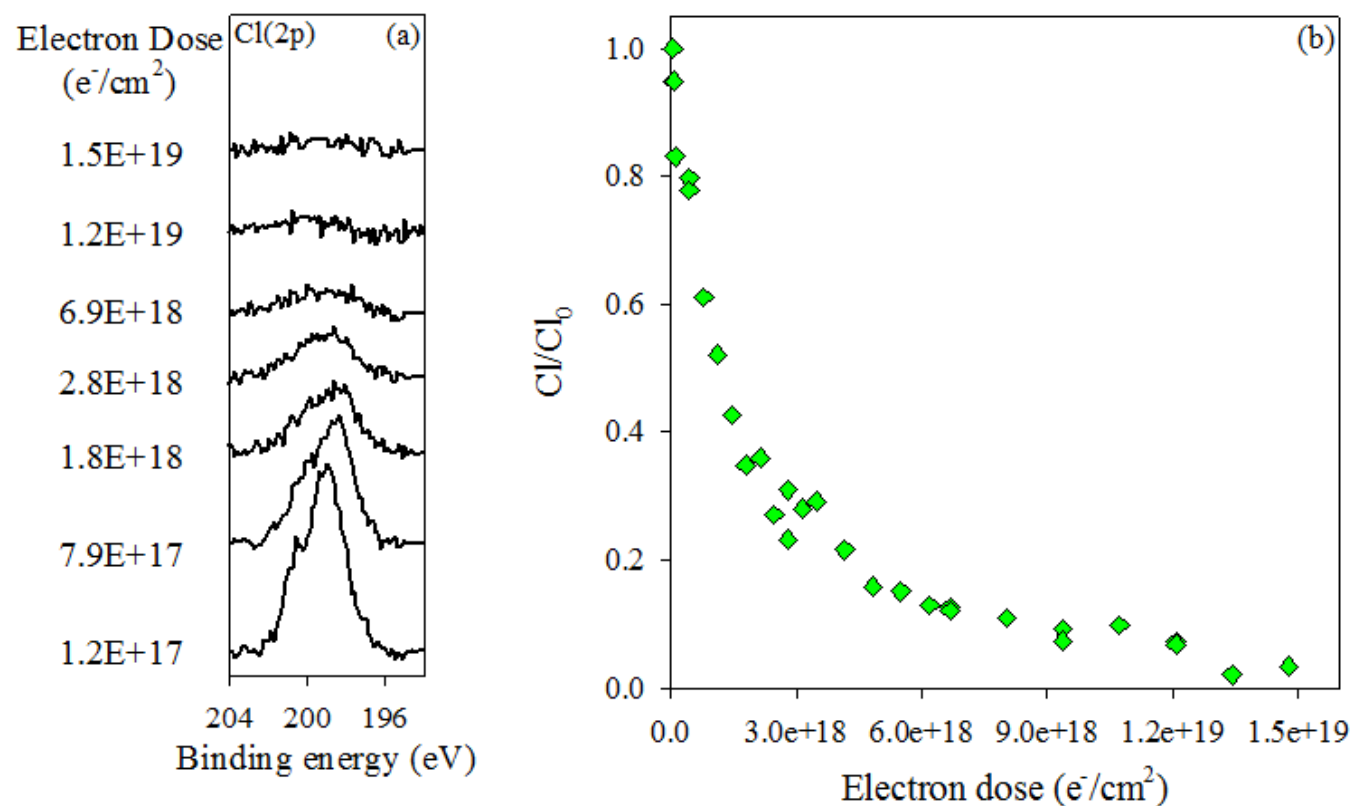
## Properties

- White/light yellow needles
- Extreme sensitivity to moisture
- Stable under CO in the freezer for months
- Sublimes under vacuum

# Electron Irradiation: *cis*-PtCl<sub>2</sub>(CO)<sub>2</sub> on SiO<sub>2</sub>

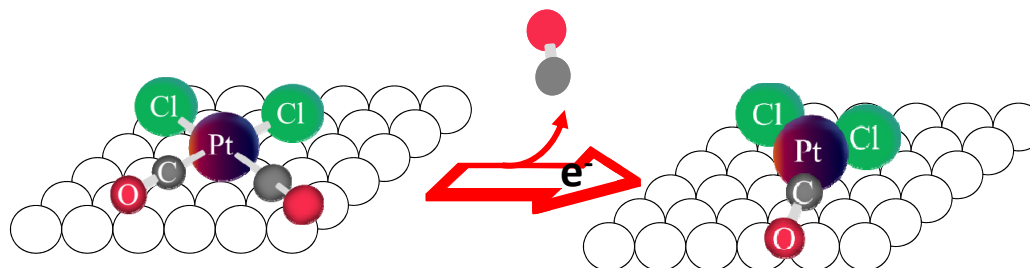


# Removal of Halide

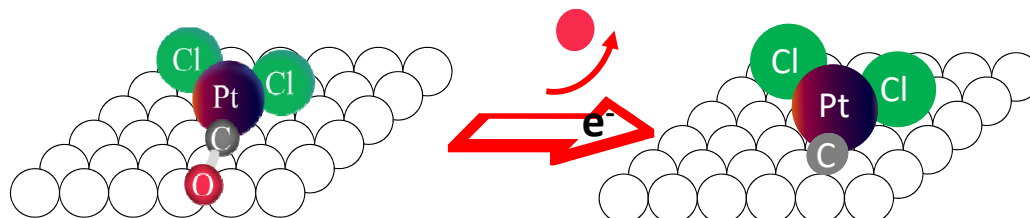


# Pt(CO)<sub>2</sub>Cl<sub>2</sub> – A Possible Route to Pt EBID

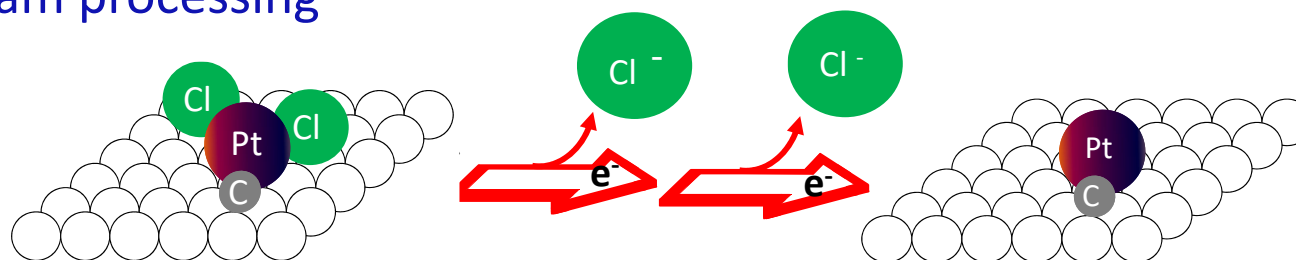
Ligand (CO) desorption



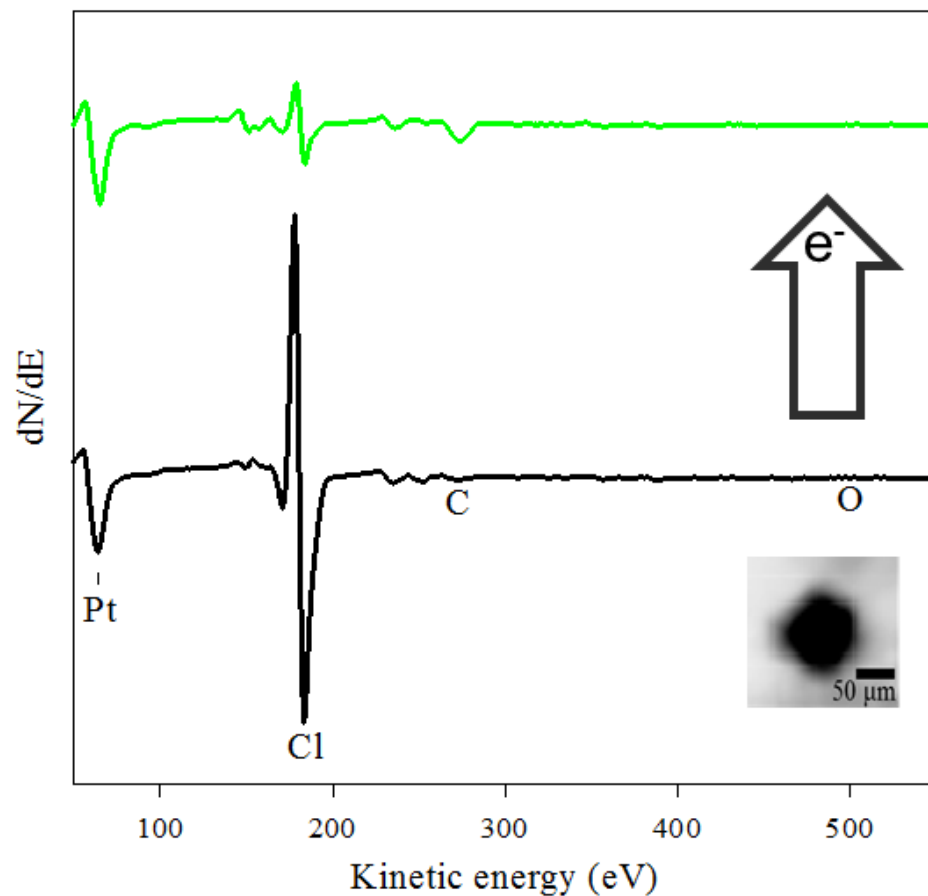
Ligand (CO) decomposition



Post-deposition e-beam processing



# EBID Structures from $\text{Pt}(\text{CO})_2\text{Cl}_2$



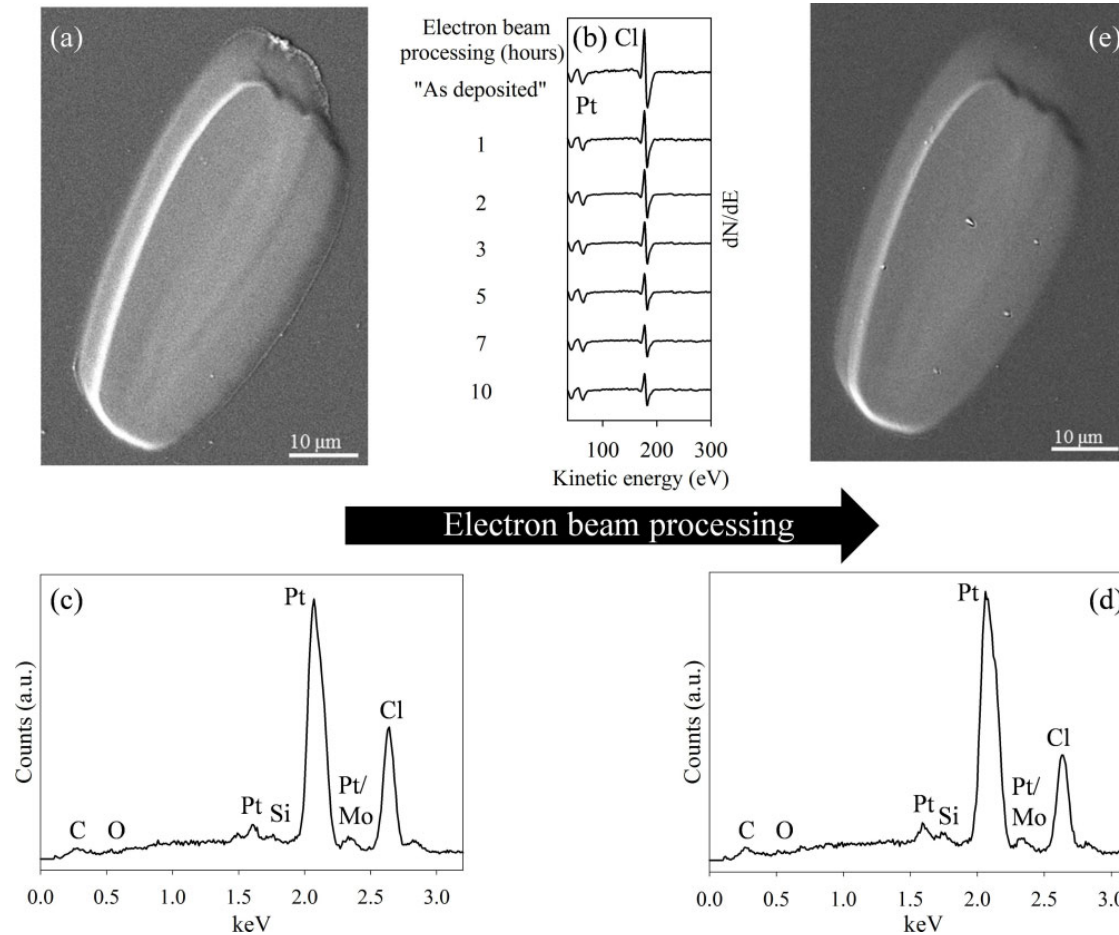
deposit after  
electron processing  
(Cl removed)

initial deposit  
(carbon and  
oxygen free)

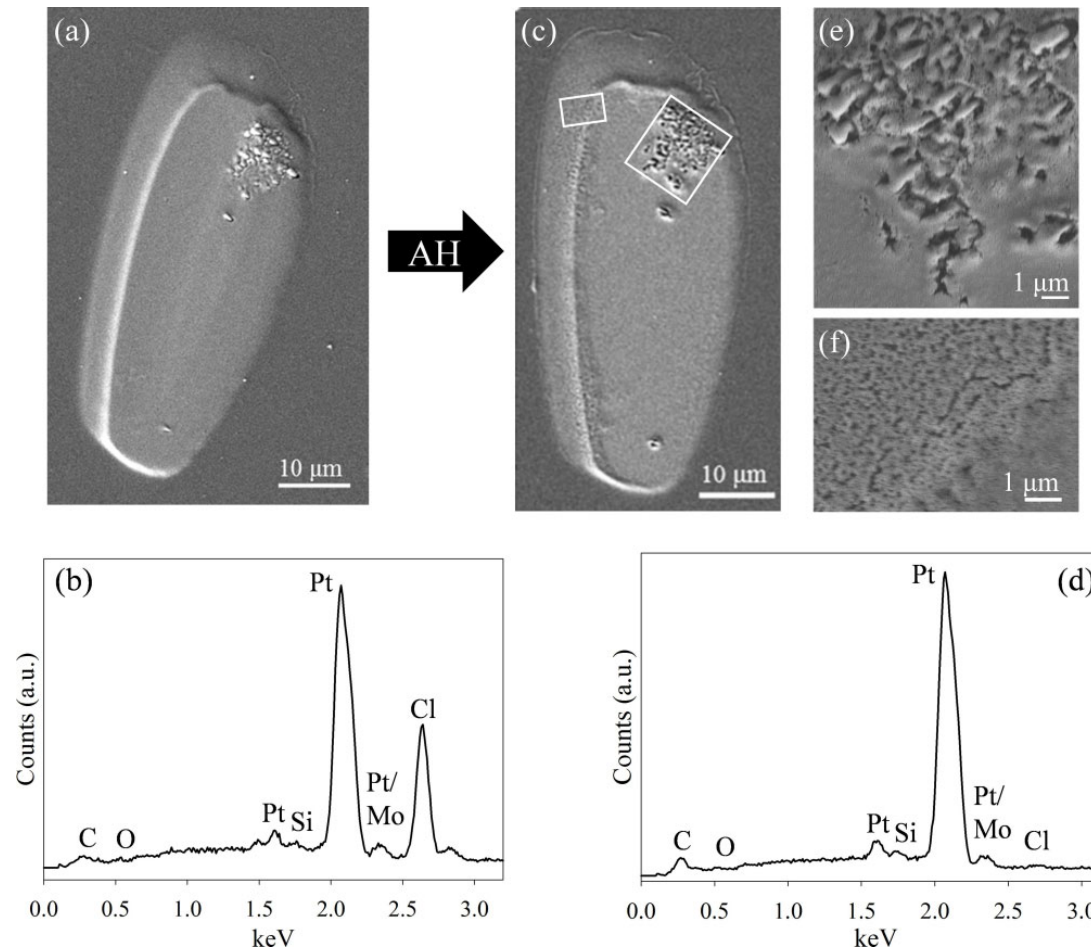
Spencer, Wu, McElwee-White, Fairbrother, *J. Am. Chem. Soc.*, **2016**, 138, 9172

Spencer, Barclay, Gallagher, Winkler, Unlu, Wu, Plank, McElwee-White, Fairbrother, *Beilstein J. Nanotech.*, **2017**, 8, 2410

# Purification of Pt FEBID Deposits - Electrons

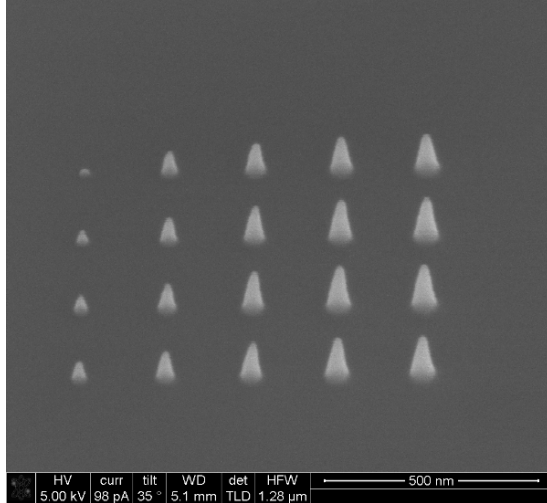


# Purification of Pt FEBID Deposits – Atomic H





# Pt(CO)<sub>2</sub>Cl<sub>2</sub> – FEBID



**Results are highly dependent on reaction conditions!**

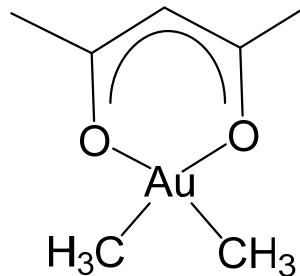
- Deposited at: 18 KeV, 38pA
- Dwell time per pixel per pass: 0.5 → 20 ms
- Refresh time: 10 ms
- 100 Passes

Element	PtCl <sub>2</sub> (CO) <sub>2</sub>	
	Before plasma	After plasma
C	53,5	47,8
Pt	21,1	27
Si	5,7	5,7
O	7,4	6,6
N	4,5	4,9
Br	---	---
Cl	7,8	7,9

# Au FEBID Precursors: A Partial History

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The common commercial precursor is  $\text{Au}(\text{acac})\text{Me}_2$



Deposit Au but are too unstable:  $\text{ClAuCO}$  and  $\text{ClAuPF}_3$

Also reported:  $\text{MeAuPMe}_3$

- $\text{ClAuPMe}_3$  and  $\text{ClAu}(\text{SMe}_2)$  could not be delivered in the gas phase

Mulders, Veerhoek, Bosch, Trompenaars, *J. Phys. D-Appl. Phys.* **2012**, 45, 475301

Utke, Hoffmann, Dwir, Leifer, Kapon, Doppelt, *J. Vac. Sci. Technol. B* **2000**, 18, 3168

van Dorp, Wu, Mulders, Harder, Rudolf, De Hosson, *Langmuir* **2014**, 30, 12097

# Volatility of Au(I) Complexes

Compound	T <sub>sub</sub> (°C) <sup>a</sup> 125 mTorr <sup>b</sup>	T <sub>dec</sub> (°C) 760 Torr
ClAuCN <sup>t</sup> Bu	64	162
BrAuCN <sup>t</sup> Bu	53	147
IAuCN <sup>t</sup> Bu	51	96
ClAuCNMe	83	184
BrAuCNMe	79	204
IAuCNMe	65	174
ClAuPMe <sub>3</sub>	78	231
BrAuPMe <sub>3</sub>	83	231
IAuPMe <sub>3</sub>	70	179
ClAuP(NMe <sub>2</sub> ) <sub>3</sub>	69	183
BrAuP(NMe <sub>2</sub> ) <sub>3</sub>	73	134
IAuP(NMe <sub>2</sub> ) <sub>3</sub>	62	138
ClAuP(OCH <sub>2</sub> CF <sub>3</sub> ) <sub>3</sub>	55 <sup>c</sup>	61
BrAuP(OCH <sub>2</sub> CF <sub>3</sub> ) <sub>3</sub>	73 <sup>c</sup>	93
IAuP(OCH <sub>2</sub> CF <sub>3</sub> ) <sub>3</sub>	56 <sup>c</sup>	67

<sup>a</sup> ± 0.5 °C

<sup>b</sup> ± 1 mTorr

<sup>c</sup> melting before sublimation

# Refining the Precursor Design

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## Tunable X-Au-L scaffold

- Stability control
- Volatility control

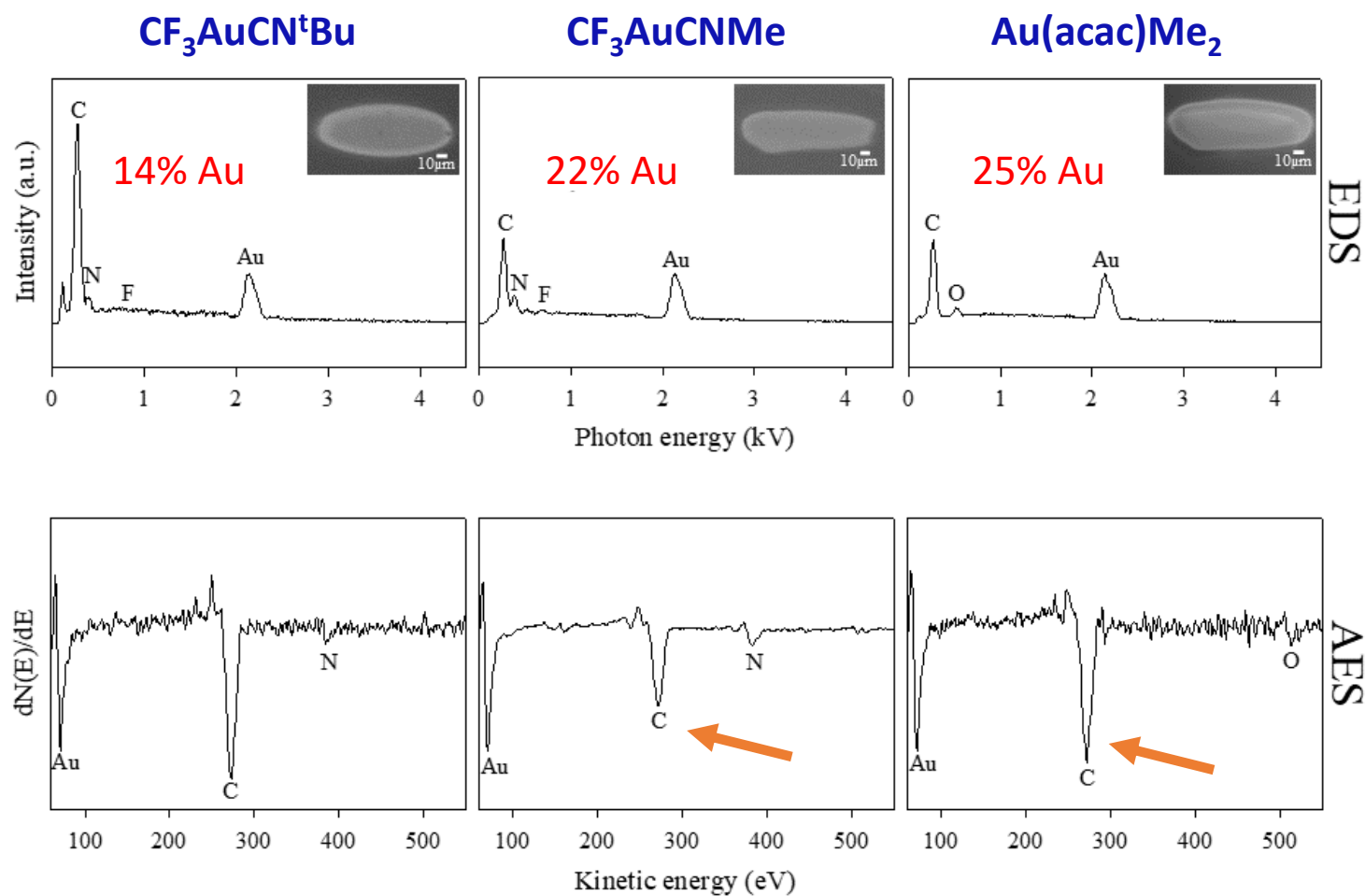
Increase size  $\rightarrow$  X—Au—L  $\leftarrow$  Increase  $\sigma$  donation

# Volatility of Au(I) Complexes

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ClAuCNMe	83 °C/125 mTorr	(onset)
ClAuCN <sup>t</sup> Bu	64 °C/125 mTorr	(onset)
CF <sub>3</sub> AuCN <sup>t</sup> Bu	57 °C/115 mTorr	(prep)
CF <sub>3</sub> AuCNMe	67 °C/115 mTorr	(prep)

# FEBID Structures (Steady State Deposition)



# What We Have Learned (So Far)

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1. Anionic  $\pi$ -facial carbon ligands such as  $\eta^5$ -Cp and  $\eta^3$ -allyl are not a good idea.
2. CO ligands can be removed under  $e^-$  irradiation.
3. Halide ligands can also be removed but may require more  $e^-$  or other reductive coreactants.
4. Volatility can be controlled by halide substitution.

# Acknowledgments

## Precursor Synthesis

Carlos Ortiz  
Benjamin Brooks  
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Randall McClain  
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Kelsea Johnson  
Richard Bonsu  
Arijit Koley  
Nathan Richey  
Joseph Brannaka  
Duane Bock  
Michelle Nolan  
Jakub Pedziwiatr  
Xiaoming Su  
Hang Lu  
Nathan Ou  
Will Carden  
Chris Brewer

## Precursor Synthesis

Alex Touchton  
Scott Matsuda  
Hanwen Liu  
Olivia Hawkins  
Persi Panariti  
Jessica Tami  
Chandler Haines  
Jo-Chi Yu  
Tim Dunn  
Thu Kim  
Ian Germaine  
Erik Ferenczy  
Courtney Sparrow  
Nick Sheehan  
Jackie Cetola  
Matthew Alderman  
Sarah Wheeler

## Electron Beam-Induced Deposition

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Ilyas Unlu

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Styrmir Svavarsson  
Ali Kamali  
Maicol Cipriani

**Dr. Aurélien Botman (FEI/ThermoFisher)**

**Dr. Ivo Utke (EMPA)**

Jakub Jurczyk

**Prof. Harald Plank (TU Graz)**

**Prof. Kees Hagen (TU Delft)**

Aya Mahgoub

**Dr. Jaroslav Jiruše (Tescan)**





# The Group

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